



00862.022032.

PATENT APPLICATION

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re Application of:)
 :
 HIROSHI TSUJI ET AL.)
 :
 Application No.: 09/691,234)
 :
 Filed: October 19, 2000)
 :
 For: ELECTRON BEAM LITHOGRAPHY)
 APPARATUS : February 24, 2003

Examiner: J. Berman
Group Art Unit: 2881

*9/A And
COF
3-18-03
Pwalle*

Commissioner For Patents
Washington, D.C. 20231

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AMENDMENT AND
PETITION FOR EXTENSION OF TIME

Sir:

INTRODUCTORY COMMENTS

Applicants petition to extend the time for response to the Office Action of August 22, 2002 to Saturday, February 22, 2003. A check in the amount of \$930.00 in payment of the extension fee is enclosed. Please charge any additional fee and credit any overpayment to our Deposit Account 06-1205.

In response to that Office Action, please amend the above-identified application as follows:

I hereby certify that this correspondence is being deposited with the United States Postal Service as first-class mail in an envelope addressed to: Assistant Commissioner for Patents, Washington, D.C. 20231 on February 24, 2003.
(Date of Deposit)

03/04/2003 ANABI1 00000074 09691234
01 FC:1253 930.00 OP

FRANK A. DeLUCIA
(Name of Attorney for Applicant)
Frank DeLucia
Signature
February 24, 2003
Date of Signature